Weijuan Qu

List of Publications by Year
in descending order

Source: https://exaly.com/author-pdf/10536836/publications.pdf

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30	867	687363 13	610901 24
papers	citations	h-index	g-index

30	30	30	467
all docs	docs citations	times ranked	citing authors

#	Article	IF	Citations
1	High-speed transport-of-intensity phase microscopy with an electrically tunable lens. Optics Express, 2013, 21, 24060.	3.4	172
2	Phase aberration compensation in digital holographic microscopy based on principal component analysis. Optics Letters, 2013, 38, 1724.	3.3	140
3	Noninterferometric single-shot quantitative phase microscopy. Optics Letters, 2013, 38, 3538.	3.3	128
4	Quasi-physical phase compensation in digital holographic microscopy. Journal of the Optical Society of America A: Optics and Image Science, and Vision, 2009, 26, 2005.	1.5	65
5	Boundary-artifact-free phase retrieval with the transport of intensity equation II: applications to microlens characterization. Optics Express, 2014, 22, 18310.	3.4	45
6	Transmission digital holographic microscopy based on a beam-splitter cube interferometer. Applied Optics, 2009, 48, 2778.	2.1	41
7	Simple and flexible phase compensation for digital holographic microscopy with electrically tunable lens. Applied Optics, 2017, 56, 6007.	1.8	40
8	Phase retrieval with the transport-of-intensity equation in an arbitrarily shaped aperture by iterative discrete cosine transforms. Optics Letters, 2015, 40, 1976.	3.3	36
9	Direct continuous phase demodulation in digital holography with use of the transport-of-intensity equation. Optics Communications, 2013, 309, 221-226.	2.1	34
10	Quantitative measurement of thermal lensing in diode-side-pumped Nd:YAG laser by use of digital holographic interferometry. Optics Express, 2016, 24, 28185.	3.4	23
11	Off-axis tilt compensation in common-path digital holographic microscopy based on hologram rotation. Optics Letters, 2017, 42, 5282.	3.3	23
12	Characterization and inspection of microlens array by single cube beam splitter microscopy. Applied Optics, 2011, 50, 886.	2.1	18
13	Phase aberration compensation for digital holographic microscopy based on geometrical transformations. Journal of Optics (United Kingdom), 2019, 21, 085702.	2.2	17
14	Wavelength dependence of light-induced domain nucleation in MgO-doped congruent LiNbO3 crystal. Applied Physics Letters, 2007, 90, 042904.	3.3	13
15	Phase mapping of domain kinetics in lithium niobate by digital holographic interferometry. Journal of Applied Physics, 2009, 105, .	2.5	13
16	Ridge-shape phase distribution adjacent to 180Â° domain wall in congruent LiNbO3 crystal. Applied Physics Letters, 2006, 89, 112912.	3.3	11
17	Further investigation on the phase stitching and system errors in digital holography. Applied Optics, 2015, 54, 266.	1.8	11
18	Phase Retrieval for Digital Holographic Microscopy With Defocused Holograms. IEEE Photonics Journal, 2018, 10, 1-9.	2.0	7

#	Article	IF	Citations
19	Diffraction properties of volume holographic gratings for an ultrashort pulsed beam with different polarization states readout. Journal of Modern Optics, 2006, 53, 1931-1945.	1.3	6
20	Investigation of effective internal field in congruent lithium niobate crystal by digital holographic interferometry. Applied Physics Letters, 2007, 90, 032903.	3.3	6
21	Focal length calibration of an electrically tunable lens by digital holography. Applied Optics, 2016, 55, 749.	2.1	6
22	Measurement of thermal effects of diode-pumped solid-state laser by using digital holography. Applied Optics, 2018, 57, 5385.	1.8	5
23	A new phase error compensation method in digital holographic microscopy. Proceedings of SPIE, 2015, , .	0.8	3
24	Fast Aberrations Compensation in Digital Holographic Microscopy Based on Phase Transformation. IEEE Photonics Journal, 2020, 12, 1-9.	2.0	3
25	Quantitative phase measurement for wafer-level optics. , 2015, , .		1
26	A quantitative phase imaging system based on transport-of-intensity equation. , 2015, , .		0
27	Phase errors elimination in compact digital holoscope (CDH) based on a reasonable mathematical model. , 2015, , .		0
28	A reflection TIE system for 3D inspection of wafer structures. , 2017, , .		0
29	Quasicommon-path digital holographic microscopy with phase aberration compensation based on a long-working distance objective. Optical Engineering, 2018, 57, 1.	1.0	0
30	Automatic phase aberration compensation for digital holographic microscopy based on rotation and transpose. , 2019, , .		0